



Substitute Form PTO-1449 (Revised)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 12816-018001	Application No. 09/882,289
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Helmut Wurzer et al.	
		Filing Date June 15, 2001	Group Art Unit 1763

U.S. Patent Documents							
Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
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	AH						
	AI						
	AJ						
	AK						

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Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
gag	AL	DE 38.32.450	04/27/1989	Germany	H01L	21/76		
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
gag	AQ	Weidner, G.; Nitrogen incorporation during N ₂ O and NO-oxidation of silicon at temperatures down to 600 C. In: Microelectronics Journal, 1996, Vol. 27, No. 7, pages 647-656 (Inspect Abstract, Accession No. 1996: 5389302).
	AR	
	AS	
	AT	

Examiner Signature <i>George Gouldreau</i>	Date Considered <i>3-4-03'</i>
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	